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*AF*

RESPONSE UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE  
GROUP 1763  
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q77312

Hiroshi TANABE, et al.

Appln. No.: 10/674,396

Group Art Unit: 1763

Confirmation No.: 4416

Examiner: Karla A. MOORE

Filed: October 1, 2003

For: SEMICONDUCTOR MANUFACTURING APPARATUS AND MANUFACTURING  
METHOD OF THIN FILM SEMICONDUCTOR DEVICE

**RESPONSE UNDER 37 C.F.R. § 1.116**

**MAIL STOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated May 26, 2006, please consider the remarks as follows on the accompanying pages.

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